Search strategies for Case _No. 10005637_
Search done in WEST. Searches done 08/17-20/03
Ex. Andre' Stevenson

5430548) and (rotate$2 or rotation$2 or rotating$4) and mirror$2

USPT
5430548

USPT
((5798831)) and (rotate$2 or rotation$2 or rotating$4) and mirror$2

USPT
(5680207) and (rotate$2 or rotation$2 or rotating$4) and mirror$2

USPT
(5680207) and (rotate$2 or rotation$2 or rotating$4)

USPT
5680207

USPT
((((5680207) and matrix$2 and (light$2 or optical) near (detection or detect$2 or beam$2) and linear$2 near pattern$2))and (scan$2 or scanning) and mirror$2) and (rotate$2 or rotation$2 or rotating$4)

USPT
(((5798831))and (scan$2 or scanning) and mirror$2) and (rotate$2 or rotation$2 or rotating$4)

USPT
((5798831)) and (scan$2 or scanning) and mirror$2

USPT
(((5680207) and matrix$2 and (light$2 or optical) near (detection or detect$2 or beam$2) and linear$2 near pattern$2)) and (scan$2 or scanning) and mirror$2

USPT
((6487307)) and (scan$2 or scanning) and mirror$2

USPT
(6487307) and defect$2 and image$2 and pattern$2

USPT
(6487307) and defect$2

USPT
6487307

USPT
(6487307) and defect$2 and (light$2 or optical) near (detection or detect$2 or beam$2) and (scan$2 or scanning)and image$2 and pattern$2 and linear$2 near pattern$2 and matrix$2

USPT
6487307

USPT
(Semiconductor$2 and defect$2 and (light$2 or optical) near (detection or detect$2 or beam$2) and (scan$2 or scanning)and image$2 and pattern$2 and linear$2 near pattern$2 and matrix$2) and light$2 near beam$2

USPT
(Semiconductor$2 and defect$2 and (light$2 or optical) near (detection or detect$2 or beam$2) and (scan$2 or scanning)and image$2 and pattern$2 and linear$2 near pattern$2 and matrix$2) and light$2

USPT
Semiconductor$2 and defect$2 and (light$2 or optical) near (detection or detect$2 or beam$2) and (scan$2 or scanning)and image$2 and pattern$2 and linear$2 near pattern$2 and matrix$2

USPT
(((5430548)and (second$2 or two or additional$2) near (patteren$2 or wafer$2 or work$2))and defect$2) and (second$2 or two or additional$2)

USPT
(((5798831)and matrix$2 and (light$2 or optical) near (detection or detect$2 or beam$2) and linear$2 near pattern$2)and defect$2) and (second$2 or two or additional$2)

USPT
(((5680207)and matrix$2 and (light$2 or optical) near (detection or detect$2 or beam$2) and linear$2 near pattern$2)and defect$2) and (second$2 or two or additional$2)

USPT

((5430548)and (second$2 or two or additional$2) near (patteren$2 or wafer$2 or work$2)) and defect$2

USPT
((5798831)and matrix$2 and (light$2 or optical) near (detection or detect$2 or beam$2) and linear$2 near pattern$2) and defect$2

USPT
((5680207)and matrix$2 and (light$2 or optical) near (detection or detect$2 or beam$2) and linear$2 near pattern$2) and defect$2

USPT
((5680207)and matrix$2 and (light$2 or optical) near (detection or detect$2 or beam$2) and linear$2 near pattern$2) and (second$2 or two or additional$2) near (patteren$2 or wafer$2 or work$2)

USPT
((5798831)and matrix$2 and (light$2 or optical) near (detection or detect$2 or beam$2) and linear$2 near pattern$2) and (second$2 or two or additional$2) near (patteren$2 or wafer$2 or work$2)

USPT
(5430548) and (second$2 or two or additional$2) near (patteren$2 or wafer$2 or work$2)

USPT
(5798831) and matrix$2 and (light$2 or optical) near (detection or detect$2 or beam$2) and linear$2 near pattern$2

USPT
(5680207) and matrix$2 and (light$2 or optical) near (detection or detect$2 or beam$2) and linear$2 near pattern$2

USPT
(5430548) and matrix$2 and (light$2 or optical) near (detection or detect$2 or beam$2) and linear$2 near pattern$2

USPT
(5798831) and matrix$2 and (light$2 or optical) near (detection or detect$2 or beam$2) and linear$2 near pattern$2

USPT
5798831

USPT
5680207

USPT
((((((Semiconductor$2 and defect$2 near inspection$2)and (light$2 or optical) near (detection or detect$2 or beam$2))and (scan$2 or scanning))and image$2 and pattern$2)and linear$2 near pattern$2) and matrix$2)

USPT
5430548

USPT
(((((Semiconductor$2 and defect$2 near inspection$2)and (light$2 or optical) near (detection or detect$2 or beam$2))and (scan$2 or scanning))and image$2 and pattern$2)and linear$2 near pattern$2) and matrix$2

USPT
((((Semiconductor$2 and defect$2 near inspection$2)and (light$2 or optical) near (detection or detect$2 or beam$2))and (scan$2 or scanning))and image$2 and pattern$2) and matrix$2

USPT
((5430548)and defect$2) and (second$2 or two or additional$2) near (patteren$2 or wafer$2 or work$2)

USPT
(5430548) and defect$2

USPT
5430548

USPT
(((((Semiconductor$2 and defect$2 near inspection$2)and (light$2 or optical) near (detection or detect$2 or beam$2))and (scan$2 or scanning))and image$2 and pattern$2)and linear$2 near pattern$2) and (second$2 or two or additional$2) near (patteren$2 or wafer$2 or work$2)

USPT
((((Semiconductor$2 and defect$2 near inspection$2)and (light$2 or optical) near (detection or detect$2 or beam$2))and (scan$2scanning))and image$2 and pattern$2) and linear$2 near pattern$2

USPT
(((Semiconductor$2 and defect$2 near
inspection$2)and (light$2 or optical) near
(detection or detect$2 or beam$2))and (scan$2
or scanning)) and image$2 and pattern$2

USPT
(((Semiconductor$2 and defect$2 near
inspection$2)and (light$2 or optical) near
(detection or detect$2 or beam$2))and (scan$2
or scanning)) image$2 and pattern$2

USPT
(((Semiconductor$2 and defect$2 near
inspection$2)and (light$2 or optical) near
(detection or detect$2 or beam$2))and (scan$2
or scanning)) image

USPT
((Semiconductor$2 and defect$2 near
inspection$2)and (light$2 or optical) near
(detection or detect$2 or beam$2)) and (scan$2
or scanning)

USPT
(Semiconductor$2 and defect$2 near
inspection$2) and (light$2 or optical) near
(detection or detect$2 or beam$2)

S9991

USPT
                Semiconductor$2 and
defect$2 near inspection$2